Vishnu Chauhan

List of Publications by Year in descending order

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| # | Article | IF | CITATIONS |
|----|---|-----|-----------|
| 1 | Electronic structure engineering of 2-D MoS2 sputtered thin films under ion beam irradiation: Induced by controlled defect generation. Ceramics International, 2022, 48, 2999-3019. | 4.8 | 12 |
| 2 | Defects engineering and enhancement in optical and structural properties of 2D-MoS2 thin films by high energy ion beam irradiation. Materials Chemistry and Physics, 2022, 276, 125422. | 4.0 | 13 |
| 3 | Influence of high energy (MeV) Au9+ ion irradiation for modification of properties in scaffold-assisted electro synthesized PbSe nanowires. Inorganic Chemistry Communication, 2022, 135, 109093. | 3.9 | 1 |
| 4 | Influence of high dose gamma radiation on optical, physico-chemical and surface morphology properties of nanocrystalline ZrO2 thin films. Optical Materials, 2022, 126, 112125. | 3.6 | 6 |
| 5 | Ion beam-induced modifications in ZnO nanostructures and potential applications. , 2021, , 117-155. | | 3 |
| 6 | Phase transformation and enhanced blue photoluminescence of zirconium oxide poly-crystalline thin film induced by Ni ion beam irradiation. Scientific Reports, 2021, 11, 17672. | 3.3 | 6 |
| 7 | High energy (MeV) ion beam induced modifications in Al2O3-ZnO multilayers thin films grown by ALD and enhancement in photoluminescence, optical and structural properties. Vacuum, 2021, 192, 110435. | 3.5 | 9 |
| 8 | Phase transformation and modifications in high-k ZrO2 nanocrystalline thin films by low energy Kr5+ ion beam irradiation. Materials Chemistry and Physics, 2020, 240, 122127. | 4.0 | 17 |
| 9 | Electronic excitation induced modifications in surface morphological, optical and physico-chemical properties of ALD grown nanocrystalline Al2O3 thin films. Superlattices and Microstructures, 2020, 141, 106389. | 3.1 | 5 |
| 10 | lon beam engineering in WO3-PEDOT: PSS hybrid nanocomposite thin films for gas sensing measurement at room temperature. Inorganic Chemistry Communication, 2020, 119, 108000. | 3.9 | 18 |
| 11 | Influence of high energy ion irradiation on structural, morphological and optical properties of high-k dielectric hafnium oxide (HfO2) thin films grown by atomic layer deposition. Journal of Alloys and Compounds, 2020, 831, 154698. | 5.5 | 24 |
| 12 | High dose gamma radiation exposure upon Kapton-H polymer for modifications of optical, free volume, structural and chemical properties. Optik, 2020, 205, 164244. | 2.9 | 6 |
| 13 | Study of humidity sensing properties and ion beam induced modifications in SnO2-TiO2 nanocomposite thin films. Surface and Coatings Technology, 2020, 392, 125768. | 4.8 | 39 |
| 14 | Development of WO3-PEDOT: PSS hybrid nanocomposites based devices for liquefied petroleum gasÂ(LPG) sensor. Journal of Materials Science: Materials in Electronics, 2019, 30, 13593-13603. | 2.2 | 35 |
| 15 | High-energy 120ÂMeV Au9+ ion beam-induced modifications and evaluation of craters in surface morphology of SnO2 and TiO2 nanocomposite thin films. Applied Nanoscience (Switzerland), 2019, 9, 1265-1280. | 3.1 | 15 |
| 16 | High energy (150†MeV) Fe11+ ion beam induced modifications of physico-chemical and photoluminescence properties of high-k dielectric nanocrystalline zirconium oxide thin films. Ceramics International, 2019, 45, 18887-18898. | 4.8 | 12 |
| 17 | Dense electronic excitation induced modifications in nanocrystalline zirconium oxide thin films: Detailed analysis of optical and surface topographical. Optical Materials, 2019, 89, 576-590. | 3.6 | 14 |
| 18 | Influence of 120 MeV S9+ ion irradiation on structural, optical and morphological properties of zirconium oxide thin films deposited by RF sputtering. Physics Letters, Section A: General, Atomic and Solid State Physics, 2019, 383, 898-907. | 2.1 | 21 |

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|----|---|-----|-----------|
| 19 | Studies of the electronic excitation modifications induced by SHI of Au ions in RF sputtered ZrO2 thin films. Materials Science in Semiconductor Processing, 2018, 88, 262-272. | 4.0 | 33 |